IN THE CLAIMS

The following includes the entire set of pending claims including mark-ups.

Please amend Claims 1-9.

Please add Claims 10-20.

- 1. (currently amended) An electroconductive contact probe holder for supporting a plurality of contact units for contacting an object, comprising:
- a base plate member made of a first material and provided with an opening therein therethrough; and
- a holder hole forming member made of a second material and filled in said opening substantially without extending outside said opening;
- a plurality of holder holes being passed across a thickness of said holder hole forming member each for receiving a contact unit therein.
- 2. (currently amended) [[An]] The electroconductive contact probe holder according to claim 1, wherein said first material comprises a member selected from a group consisting of metallic material, semiconductor material, ceramic material and glass material.
- 3. (currently amended) [[An]] The electroconductive contact probe holder according to claim 1, wherein said second material comprises a plastic material.
- 4. (currently amended) [[An]] <u>The</u> electroconductive contact probe holder according to claim 1, wherein <u>a</u> film is formed over an inner circumferential surface of said opening.
- 5. (currently amended) [[An]] <u>The</u> electroconductive contact probe holder according to claim [[1]] <u>4</u>, wherein said film is made of <u>a</u> material that promotes bonding between said holder hole forming member and said base plate.
- 6. (currently amended) [[An]] <u>The</u> electroconductive contact probe holder according to claim [[1]] <u>4</u>, wherein said film is made of <u>a</u> material that promotes electric insulation between said holder hole forming member and said base plate.

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- 7. (currently amended) [[An]] <u>The</u> electroconductive contact probe holder according to claim [[1]] <u>4</u>, wherein an engagement feature is formed on [[an]] <u>the</u> inner circumferential surface of said opening.
- 8. (currently amended) [[An]] The electroconductive contact probe holder according to claim 7, wherein said base plate member is made of a silicon wafer and said engagement feature comprises an inwardly directed ridge formed by anisotropically etching said inner circumferential surface of said opening.
- 9. (currently amended) [[An]] <u>The</u> electroconductive contact probe holder according to claim 1, wherein a stress relieving opening is formed adjacent said opening having said holder hole forming portion filled therein.
- 10. (new) An electroconductive contact probe holder for supporting a plurality of contact units for contacting an object, comprising:
- a base plate member made of a first material and provided with an opening therethrough, wherein a film is formed over an inner circumferential surface of said opening; and
- a holder hole forming member made of a second material and filled in said opening substantially without extending outside said opening;
- a plurality of holder holes being passed across a thickness of said holder hole forming member each for receiving a contact unit therein.
- 11. (new) The electroconductive contact probe holder according to claim 10, wherein said first material comprises a member selected from a group consisting of metallic material, semiconductor material, ceramic material and glass material.
- 12. (new) The electroconductive contact probe holder according to claim 10, wherein said second material comprises a plastic material.
- 13. (new) The electroconductive contact probe holder according to claim 10, wherein said film is made of a material that promotes bonding between said holder hole forming member and said base plate.

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- 14. (new) The electroconductive contact probe holder according to claim 10, wherein said film is made of material that promotes electric insulation between said holder hole forming member and said base plate.
- 15. (new) The electroconductive contact probe holder according to claim 10, wherein an engagement feature is formed on the inner circumferential surface of said opening.
- 16. (new) The electroconductive contact probe holder according to claim 15, wherein said base plate member is made of a silicon wafer and said engagement feature comprises an inwardly directed ridge formed by anisotropically etching said inner circumferential surface of said opening.
- 17. (new) The electroconductive contact probe holder according to claim 10, wherein a stress relieving opening is formed adjacent said opening having said holder hole forming portion filled therein.
- 18. (new) An electroconductive contact probe holder for supporting a plurality of contact units for contacting an object, comprising:
- a base plate member made of a first material and provided with an opening therethrough, wherein said first material comprises a member selected from a group consisting of metallic material, semiconductor material, ceramic material, and glass material; and
- a holder hole forming member made of a second material and filled in said opening substantially without extending outside said opening;
- a plurality of holder holes being passed across a thickness of said holder hole forming member each for receiving a contact unit therein.
- 19. (new) The electroconductive contact probe holder according to claim 18, wherein a film is formed over an inner circumferential surface of said opening, said film being made of a material that promotes bonding between said holder hole forming member and said base plate.

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20. (new) The electroconductive contact probe holder according to claim 18, wherein a film is formed over an inner circumferential surface of said opening, said film being made of a material that promotes electric insulation between said holder hole forming member and said base plate.

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